



PATENT
8565D-7213 (81839.0077)

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:

Teruaki FUKAMI

Serial No: 09/218,997

Filed: December 22, 1998

For: SILICON WAFER STORAGE WATER
AND SILICON WAFER STORAGE
METHOD

RECEIVED

TC 1700

Art Unit: 1744

Examiner: Soubra, I.

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RESPONSE TO FINAL OFFICE ACTION
UNDER 37 C.F.R. § 1.116

Box Non-Fee Amendment
Commissioner for Patents
Washington, D.C. 20231

Dear Sir:

In response to the Final Office Action dated June 18, 2001, please
enter and consider the following remarks:

REMARKS

Claims 1-20 are pending in the application. On the first six pages of the
Office Action of June 18, 2001, beginning with "DETAILED ACTION," claims 1-20
are rejected on various combinations of prior art references under 35 U.S.C.
§ 103(a). The rejections are essentially a repeat of the rejections made in the prior
Office Action of March 1, 2001. On the sixth and seventh pages of the Office Action,
applicant's prior arguments are summarized. On the seventh page, responses to
Applicants Arguments are set forth.

These rejections are again respectfully traversed for the reasons set forth
below.